

IFW

MICRON.230DV1

PATENT



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Liu et al.  
App. No. : 10/734,663  
Filed : December 11, 2003  
For : METHOD FOR MANUFACTURE  
OF MAGNETO-RESISTIVE BIT  
STRUCTURE  
Examiner : Kathleen Duda

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

June 9, 2005

(Date)

*Adeel S. Akhtar*

Adeel S. Akhtar, Reg. No. 41,394

STATUS LETTER

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Our file for the subject application reveals that there has been no action in this application since it was filed, i.e., December 11, 2003.

Please inform us as to the status of this application.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: June 9, 2005

By: *Adeel S. Akhtar*

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